

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1 - 11 (canceled)

12. (currently amended) A vacuum processing apparatus comprising:

a transfer box inside of which an object wafer to be processed is transferred under an atmospheric condition by a transfer robot disposed therein, the transfer box ~~having enabling holding of~~ a plurality of wafer cassettes installed at a front ~~surface~~ side portion thereof;

a vacuum transfer ~~chamber-unit~~ disposed at a ~~rear surface~~ back side portion of the transfer box and detachably-connected thereto coupled to a back side surface portion of the transfer box, the vacuum transfer ~~chamber-unit~~ enabling transfer of the object wafer therein under a vacuum condition;

at least one vacuum processing chamber disposed at a ~~rear or back or lateral~~ side of the vacuum transfer ~~chamber-unit~~ and being detachably connected thereto, the at least one vacuum processing chamber being supplied with gas and enabling processing of the object wafer transferred under the vacuum condition by a plasma generated therein; and

a plurality of connector portions of utility paths which connect with paths arranged in another floor of a building different from a floor of the building in which the vacuum processing apparatus is installed so that the at least one vacuum processing chamber is disposed above the floor, the plurality of connector portions

being disposed substantially linearly under a connecting portion of the ~~transfer box~~
~~and the vacuum transfer chamber unit~~, and being disposed at the rear ~~the back side~~
surface portion of the transfer box and along the back side surface;

wherein the utility paths enable supply of utilities including the gas supplied
from ~~[[a]]~~ building having the vacuum processing apparatus installed therein to the
vacuum transfer ~~chamber unit~~ or the at least one vacuum processing chamber and
enables discharge of exhaust from the vacuum transfer ~~chamber unit~~ or the at least
one vacuum processing chamber including the utilities supplied thereto.

13. (currently amended) A vacuum processing apparatus comprising:

an atmospheric block including a transfer box inside of which an object wafer
to be processed is transferred under an atmospheric condition by a transfer robot
disposed therein, the transfer box ~~having~~ enabling holding of a plurality of wafer
cassettes installed at a front side surface portion thereof;

a vacuum transfer ~~chamber unit~~ disposed at a rear back side of a back side
surface portion of the transfer box and detachably connected thereto by a connection
portion thereof, the vacuum transfer ~~chamber unit~~ enabling transfer of the object
wafer therein under a vacuum condition;

a vacuum processing block, installed at a connecting portion of the vacuum
transfer ~~chamber unit~~ and the transfer box;

~~at least one~~ a plurality of vacuum processing ~~chamber chambers~~ of the
vacuum processing block being disposed at a rear ~~or back or lateral~~ side of the
vacuum transfer ~~chamber unit~~ and being detachably connected thereto, ~~[[the]]~~ at
least one of the vacuum processing transfer ~~chambers~~ being supplied with gas and
enabling processing of the object wafer transferred under the vacuum condition by a

plasma generated therein, the vacuum processing block comprising the vacuum transfer unit and the plurality of vacuum processing chambers; and

a plurality of connector portions of utility paths which connect with paths arranged in another floor of a building different from a floor of the building in which the vacuum processing apparatus is installed so that the plurality of vacuum processing chambers are disposed above the floor, the plurality of connector portions being disposed substantially linearly under a connecting portion of the transfer box and the vacuum transfer-chamber unit, and being disposed at the rear along the back side surface portion of the transfer box in the back side thereof;

wherein the utility paths enables supply of utilities including the gas supplied from a building having the vacuum processing apparatus installed therein to the vacuum transfer chamber-unit or the at least one of the vacuum processing chamber chambers and enable discharge of exhaust from the vacuum transfer chamber-unit or the at least one of the vacuum processing chamber-chambers including the utilities supplied thereto.

14. (currently amended) The vacuum processing apparatus according to claim 12, wherein the utilities include plural kinds of gases, water[,] and air supplied from the building.

15. (canceled)

16. (canceled)

17. (currently amended) The vacuum processing apparatus according to claim 14, wherein the connector portions of the utility paths are disposed under at least one load lock chamber consisting of the connection portion between the transfer box and the vacuum transfer-chamber unit.

18. (currently amended) The vacuum processing apparatus according to claim 14, further comprising display units disposed at the rear back side surface portion of the transfer box and enable display of a status of the utility.

19. (currently amended) The vacuum processing apparatus according to claim 13, wherein the utilities include plural kinds of gases, water[[,]] and air supplied arranged from the building.

20. (canceled)

21. (canceled)

22. (currently amended) The vacuum processing apparatus according to claim 19, wherein the connector portions of the utility paths are disposed under at least one load lock chamber consisting of the connection portion between the transfer box and the vacuum transfer ~~chamber~~ unit.

23. (currently amended) The vacuum processing apparatus according to claim 13, further comprising display units disposed at the rear back side surface portion of the transfer box and enable display of a status of the utility.